

ABSTRACT

Provided herein are a method and an apparatus for examining foreign matters in through holes, which can quickly conduct an examination of foreign matter in through holes with low costs and high accuracy. Light passing through a plurality of through holes having a uniform size is simultaneously taken as image data, the number of areas of the imaged masses corresponding to the plurality of the respective through holes is initially counted, and a process to determine presence or absence of foreign matters is conducted by mutually comparing areas of adjacent masses for only a work piece with a counted value of the masses being concurred with a specified value.

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